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JAPANESE PATENT OFFICE

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(54) LIQUID RAW MATERIAL SUPPLYING DEVICE  
FOR CVD

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(57) Abstract:

PROBLEM TO BE SOLVED: To provide a raw material supplying device for CVD with which the continuous supply of a specified amt. of liquid raw material is possible, the improvement in film forming efficiency is possible and thin films, such as oxide superconducting thin films, having stable characteristics, such as film quality, are formable.

SOLUTION: This liquid raw material supplying device 30 for CVD includes a cylindrical raw material soln. supplying section 31 into which the liquid raw material is supplied, a cylindrical and convergent atomizing gas supplying section 32 which is supplied with an atomizing gas for atomizing the liquid raw material into the spacing between this raw material soln. supplying section 31 and this section and a cylindrical shielding gas supplying section 33 which is disposed to enclose the outer periphery of this atomizing gas supplying section 32 and is supplied with a shielding gas for cooling and shielding the raw material soln. supplying section 31 and the atomizing gas supplying section 32 into the spacing between the atomizing gas supplying section 32 and this section.

